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Susan Y. Stiles
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Docket: 0756-13637/24/96

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of)
Hisashi OHTANI et al.)
Serial No. 08/479,211) Art Unit: 1104
Filed: June 7, 1995) Examiner: L. Radomsky
For: METHOD FOR MANUFACTURING)
SEMICONDUCTOR DEVICE) Date: July 8, 1996

AMENDMENT

Honorable Commissioner of Patents and Trademarks

Washington, D.C. 20231

Sir:

In response to the Office Action of March 18, 1996, please amend the subject application as follows:

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In the Claims:

Please amend claim 1 as follows:

1. (Amended) A method of manufacturing a semiconductor device comprising the steps of:

forming a semiconductor film comprising silicon in contact with a silicon nitride film;

forming a continuous layer of a material including a catalyst capable of promoting a crystallization of silicon onto at least a portion of said semiconductor film;

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